

1	<b>PROCESSES JOINING INDEPENDENT CRYSTALS</b>	20	...Comprising a silicon crystal with oxygen containing impurity
2	<b>PROCESSES OF GROWTH WITH A SUBSEQUENT STEP ACTING ON THE CRYSTAL TO ADJUST THE IMPURITY AMOUNT (E.G., DIFFUSING, DOPING, GETTERING, IMPLANTING)</b>	21	...Comprising a semiconductor with a charge carrier impurity
3	<b>PROCESSES OF GROWTH WITH A SUBSEQUENT STEP OF HEAT TREATING OR DELIBERATE CONTROLLED COOLING OF THE SINGLE-CRYSTAL</b>	22	...Forming adjoining crystals of different compositions (e.g., junction)
4	<b>PROCESSES OF GROWTH FROM SOLID OR GEL STATE (E.G., SOLID PHASE RECRYSTALLIZATION)</b>	23	..Shape defined by a solid member other than seed or product (e.g., edge-defined film-fed growth, Stepanov method)
5	.Organic product	24	...Embedded in product (e.g., string-stabilized web)
6	.At pressure above 1 atmosphere	25	...Defines a product with a hollow structure (e.g., tube)
7	.Using heat (e.g., strain annealing)	26	...Defines a flat product
8	..Of amorphous precursor	27	...Pulling includes a horizontal component
9	..Epitaxy formation	28	..Including non-coincident axes of rotation (e.g., relative eccentric)
10	..Using temperature gradient (e.g., moving zone recrystallization)	29	..Passing non-induced electric current through a crystal-liquid interface (e.g., Peltier)
11	<b>PROCESSES OF GROWTH FROM LIQUID OR SUPERCRITICAL STATE</b>	30	..With liquid flow control or manipulation during growth (e.g., mixing, replenishing, magnetic levitation, stabilization, convection control, baffle)
12	.Crucibleless process having movement of discrete droplets or solid particles to thin-film precursor (e.g., Verneuil method)	31	...Including a sectioned crucible (e.g., double crucible, baffle)
13	.Having pulling during growth (e.g., Czochralski method, zone drawing)	32	...Using a magnetic field
14	..With a step of measuring, testing, or sensing (e.g., using TV, photo, or X-ray detector or weight changes)	33	...Replenishing of precursor during growth (e.g., continuous method, zone pulling)
15	...With responsive control	34	...Including significant cooling or heating detail
16	...Shape defined by a solid member other than seed or product (e.g., edge-defined film-fed growth, Stepanov method)	35	..With a significant technique for (a) preliminary preparation or growth starting or (b) product handling or growth ending (e.g., arrangement of or crystallography of seed)
17	..With contact with an immiscible liquid (e.g., LEC)		
18	...Using a sectioned crucible or providing replenishment of precursor		
19	..Forming an intended mixture (excluding mixed crystal) (e.g., doped)		

36	..Precursor intentionally contains an excess component or a non-product appearing component (e.g., solvent, flux, crystal lattice modifier)	51	....Electromagnetic induction
		52	....With liquid control (e.g., vibration damping, stabilizing, melt levitation focusing coil)
37	.Having moving solid-liquid-solid region	53	.Forming a single-crystal region by liquefying a region of a single-crystal and adjusting the composition of the liquid (e.g., alloying, regrowth)
38	..Including a step of measuring, testing, or sensing		
39	..With responsive control	54	.Liquid phase epitaxial growth (LPE)
40	..Liquid precursor penetrating only a portion of a single-crystal, thereby liquefying it, and single-crystal formation therefrom which adjoins the never-liquefied portion of the single-crystal (e.g., liquid wire migration)	55	..With a step of measuring, testing, or sensing
		56	..Including change in a growth-influencing parameter (e.g., composition, temperature, concentration, flow rate) during growth (e.g., multilayer or junction or superlattice growing)
41	..Precursor composition intentionally different from product (e.g., excess component, non-product forming component, dopant, non-stoichiometric precursor, travelling solvent, flux)	57	...Including a sliding boat system
		58	..With pretreatment of epitaxy substrate (e.g., autodoping control, cleaning, polishing, leveling, masking)
42	...Product has an element in common with the unusable residual portion	59	..Including a tipping system (e.g., rotation, pivoting)
43	..Distinctly layered product (e.g., twin, SOI, epitaxial crystallization)	60	..Including a vertical dipping system
44	..Adjacent single-crystal product regions separately formed (e.g., multiple non-coextensive passes of a scanning laser)	61	..Including a sliding boat system
		62	..Electric current controlled or induced growth
45	...Non-planar crystal grown (e.g., ELO)	63	..Characterized by specified crystallography of the substrate
46	..Movement includes a horizontal component	64	..Precursor composition intentionally contains an excess component or a non-product appearing component (e.g., solvent, flux)
47	..Flat, free-standing (i.e., substrate-free) product (e.g., ribbon, film, sheet)	65	...Having an element in common
48	..Solid heating means contacting the liquid (e.g., immersed)	66	...Excess component or non-product appearing component contains an oxygen atom (e.g., hydrothermal)
49	..Liquid zone contacts only precursor and product solids (e.g., crucibleless, liquid encapsulant, float zone)	67	...Excess component or non-product appearing component contains a metal atom
50	..Liquefying by energy from an electromagnetic wave or electromagnetic particle or arc or plasma (e.g., radiant heat)		

68	..Having growth from a solution comprising a solvent which is liquid at or below 20 degrees Celsius (e.g., aqueous solution)	84	<b>FORMING FROM VAPOR OR GASEOUS STATE (E.G., VPE, SUBLIMATION)</b>
69	..With a step of measuring, testing, or sensing	85	..With a step of measuring, testing, or sensing
70	..Growth accompanied by material removal (other than the product) from solution (e.g., solvent evaporation, osmosis)	86	..With responsive control
71	..At pressure above 1 atmosphere (e.g., hydrothermal processes)	87	..Forming a platelet shape or a small diameter, elongate, generally cylindrical shape (e.g., whisker, fiber, needle, filament)
72	...Quartz (SiO <sub>2</sub> ) product	88	..With decomposition of a precursor (except impurity or dopant precursor) composed of diverse atoms (e.g., CVD)
73	..Having growth from molten state (e.g., solution melt)	89	..Including change in a growth-influencing parameter (e.g., composition, temperature, concentration, flow rate) during growth (e.g., multilayer or junction or superlattice growing)
74	..Including change in a growth-influencing parameter (e.g., composition, temperature, concentration, flow rate) during growth (e.g., multilayer or junction or superlattice growing)	90	...With pretreatment of substrate (e.g., coating ablating)
75	..Forming a platelet shape or a small diameter, elongate, generally cylindrical shape (e.g., whisker, fiber, needle, filament) (e.g., VLS method)	91	...With a chemical reaction (except ionization) in a disparate zone to form a precursor
76	..Using a scavenger agent (e.g., remove, add, deplete, or redistribute impurity or dopant)	92	...Using an energy beam or field, a particle beam or field, or a plasma (e.g., ionization, PECVD, CBE, MOCVD, RF induction, laser)
77	..Gas or vapor state precursor or overpressure	93	...With significant flow manipulation or condition, other than merely specifying the components or their sequence or both
78	..Precursor composition intentionally different from product (e.g., excess component, non-product forming component, dopant, non-stoichiometric precursor, solvent, flux)	94	..With pretreatment or preparation of a base (e.g., annealing)
79	..Unusable portion contains a metal atom (e.g., diamond or CBN growth in metal solvent)	95	...Coating (e.g., masking, implanting)
80	...Unusable portion contains an oxygen atom (e.g., oxide flux)	96	....For autodoping control
81	..Growth confined by a solid member other than seed or product (e.g., Bridgman-Stockbarger method)	97	...Material removal (e.g., etching, cleaning, polishing)
82	...Including vertical precursor-product interface (e.g., horizontal Bridgman)	98	..With a movement of substrate or vapor or gas supply means during growth (e.g., substrate rotation)
83	...Having bottom-up crystallization (e.g., VFG, VGF)	99	..With a chemical reaction (except ionization) in a disparate zone to form a precursor (e.g., transport processes)

100	...Fully-sealed or vacuum-maintained chamber (e.g., ampoule)	207	..Crucibleless apparatus having means providing movement of discrete droplets or solid particles to thin-film precursor (e.g., Verneuil method)
101	..Characterized by specified crystallography or arrangement of substrate (e.g., wafer cassette, Miller index)	208	..Seed pulling
102	..With significant flow manipulation or condition, other than merely specifying the components or their sequence or both	209	...Including solid member shaping means other than seed or product (e.g., EDFG die)
103	..Using an energy beam or field, a particle beam or field, or a plasma (e.g., ionization, PECVD, CBE, MOMBE, RF induction, laser)	210	...Means for forming a hollow structure (e.g., tube, polygon)
104	..Using an organic precursor (e.g., propane, metal-organic, MOCVD, MOVPE)	211	...Including means forming a flat shape (e.g., ribbon)
105	..Including change in a growth-influencing parameter (e.g., composition, temperature, concentration, flow rate) during growth (e.g., multilayer or junction or superlattice growing)	212	....Pulling includes a horizontal component
106	..With pretreatment or preparation of a base (e.g., annealing)	213	...Including a sectioned crucible (e.g., double crucible, baffle)
107	..With movement of substrate or vapor or gas supply means during growth	214	...Including details of precursor replenishment
108	..Using an energy beam or field, a particle beam or field, or a plasma (e.g., MBE)	215	...Including sealing means details
109	..Fully-sealed or vacuum-maintained chamber (e.g., ampoule)	216	...Including a fully-sealed or vacuum-maintained crystallization chamber (e.g., ampoule)
200	<b>APPARATUS</b>	217	...Including heating or cooling details (e.g., shield configuration)
201	..With means for measuring, testing, or sensing	218	...Including details of means providing product movement (e.g., shaft guides, servo means)
202	..With responsive control means	219	..Having means for producing a moving solid-liquid-solid zone
203	..With a window or port for visual observation or examination	220	...Including a solid member other than seed or product contacting the liquid (e.g., crucible, immersed heating element)
204	..With means for treating single-crystal (e.g., heat treating)	221	...Including details of a stabilizing feature
205	..For forming a platelet shape or a small diameter, elongate, generally cylindrical shape (e.g., whisker, fiber, needle, filament)	222	...Including heating or cooling details
206	..For crystallization from liquid or supercritical state	223	..Shape defined by a solid member other than seed or product (e.g., Bridgman-Stockbarger)
		224	..Including pressurized crystallization means (e.g., hydrothermal)

**CROSS-REFERENCE ART COLLECTIONS**

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| <p>900 APPARATUS CHARACTERIZED BY COMPOSITION OR TREATMENT THEREOF (E.G., SURFACE FINISH, SURFACE COATING)</p> <p>901 LEVITATION, REDUCED GRAVITY, MICROGRAVITY, SPACE</p> <p>902 SPECIFIED ORIENTATION, SHAPE, CRYSTALLOGRAPHY, OR SIZE OF SEED OR SUBSTRATE</p> <p>903 DENDRITE OR WEB OR CAGE TECHNIQUE</p> <p>904 LASER BEAM</p> <p>905 ELECTRON BEAM</p> <p>906 SPECIAL ATMOSPHERE OTHER THAN VACUUM OR INERT</p> <p>907 .Refluxing atmosphere</p> <p>910 DOWNWARD PULLING</p> <p>911 SEED OR ROD HOLDERS</p> <p>912 REPLENISHING LIQUID PRECURSOR, OTHER THAN A MOVING ZONE</p> <p>913 GRAPHOEPITAXY OR SURFACE MODIFICATION TO ENHANCE EPITAXY</p> <p>914 CRYSTALLIZATION ON A CONTINUOUS MOVING SUBSTRATE OR COOLING SURFACE (E.G., WHEEL, CYLINDER, BELT)</p> <p>915 SEPARATING FROM SUBSTRATE</p> <p>916 OXYGEN TESTING</p> <p>917 MAGNETIC</p> <p>918 SINGLE-CRYSTAL WAVEGUIDE</p> <p>919 .Organic</p> <p>920 SINGLE-CRYSTALS HAVING A HOLLOW (E.G., TUBE, CONCAVO-CONVEX) {C30B 29/66}</p> <p>921 SMALL DIAMETER, ELONGATE, GENERALLY CYLINDRICAL SINGLE-CRYSTAL (E.G., WHISKERS, NEEDLES, FILAMENTS, FIBERS, WIRES) {C30B 29/62}</p> <p>922 FREE-STANDING, FLAT SINGLE-CRYSTAL (E.G., PLATELET, PLATE, STRIP, DISK, TAPE, SHEET, RIBBON) {C30B 29/64}</p> <p>923 SINGLE-CRYSTAL OF COMPLEX GEOMETRY (E.G., PATTERNED, ELO) {C30B 29/66}</p> <p>924 HOMOGENEOUS COMPOSITION PRODUCT WITH ENLARGED CRYSTALS OR ORIENTED-CRYSTALS (E.G., COLUMNAR)</p> <p>925 ORGANIC COMPOUND CONTAINING SINGLE-CRYSTAL {C30B 29/54}</p> | <p>926 .Tartrate containing (e.g., Rochelle salt) {C30B 29/56}</p> <p>927 .Macromolecular compound containing (i.e., more than about 100 atoms) {C30B 29/58}</p> <p>928 SINGLE-CRYSTAL OF PURE OR INTENTIONALLY DOPED ELEMENT {C30B 29/02}</p> <p>929 .Carbon (e.g., diamond) {C30B 29/04}</p> <p>930 .Silicon from solid or gel state {C30B 29/06}</p> <p>931 .Silicon from liquid or supercritical state {C30B 29/06}</p> <p>932 ..By pulling {C30B 29/06}</p> <p>933 ..By moving zone (not Verneuil) {C30B 29/06}</p> <p>934 ..By liquid phase epitaxy {C30B 29/06}</p> <p>935 .Silicon from vapor or gaseous state {C30B 29/06}</p> <p>936 .Germanium {C30B 29/08}</p> <p>937 INORGANIC CONTAINING SINGLE-CRYSTAL (E.G., COMPOUND, MIXTURE, COMPOSITE) {C30B 29/10}</p> <p>938 .Gold, silver, or platinum containing {C30B 29/52}</p> <p>939 .Free metal or intermetallic compound or silicon-metal compound based, except arsenic (e.g., alloys, SiGe, InSb) {C30B 29/40, 29/52}</p> <p>940 .Halide containing (e.g., fluorphlogopite, fluor-mica) {C30B 29/12}</p> <p>941 .Phosphorus-oxygen bond containing (e.g., phosphate (PO<sub>4</sub>)) {C30B 29/14}</p> <p>942 .Silicon-oxygen bond containing (e.g., emerald, beryl, garnet, mica) {C30B 29/16}</p> <p>943 ..Quartz (SiO<sub>2</sub>) {C30B 29/18}</p> <p>944 .Oxygen compound containing (e.g., yttria stabilized zirconia) {C30B 29/16}</p> |
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- 945 ..Containing A3Me5O12  
(1.5(A2O3):2.5(Me2O3)),  
wherein A is trivalent and  
selected from the group Sc, Y,  
La, Hf, or a rare earth metal  
and Me is trivalent and  
selected from the group Fe,  
Ga, Sc, Cr, Co, or Al (e.g.,  
non-silicate garnets) {C30B  
29/28}
- 946 ..Containing AMe2O4 (AO:(Me2O3)),  
wherein A is divalent and  
selected from the group Mg,  
Ni, Co, Mn, Zn, or Cd and Me is  
trivalent and selected from  
the group Fe, Ga, Sc, Cr, Co,  
or Al (e.g., spinels) {C30B  
29/26}
- 947 ..Containing AMeO3  
((A2O3):(Me2O3)), wherein A is  
trivalent and selected from  
the group Sc, Y, La, Hf, or a  
rare earth metal and Me is  
trivalent and selected from  
the group Fe, Ga, Sc, Cr, Co,  
or Al (e.g., Perovskite  
structure, ortho-ferrites)  
{C30B29/24}
- 948 ..Niobate, vanadate, or tantalate  
containing {C30B 29/30}
- 949 ..Titanate, germanate, molybdate,  
or tungstate containing {C30B  
29/32}
- 950 ..Aluminum containing (e.g.,  
AL2O3, ruby, corundum,  
sapphire, chrysoberyl) {C30B  
29/20}
- 951 ..Carbide containing (e.g., SiC)  
{C30B 29/36}
- 952 ..Nitride containing (e.g., GaN,  
cBN) {C30B 29/38}
- 953 ..{B,Al,Ga,In,Tl}{P,As,Sb,Bi}  
compound containing, except  
intermetallics thereof (i.e.,  
except {Al,Ga,In,Tl}{Sb,Bi})  
{C30B 29/40}
- 954 ..Gallium arsenide containing  
(e.g., GaAlAs, GaAs) {C30B 29/  
42}
- 955 ..Gallium phosphide containing  
{C30B 29/44}
- 956 ..{Zn,Cd,Hg}{S,Se,Te} compound  
containing {C30B 29/46}
- 957 ..CdHgTe containing {C30B 29/48}
- 958 ..Cadmium sulfide containing  
(e.g., ZnCdS) {C30B 29/50}

**FOREIGN ART COLLECTIONS**

FOR 000 CLASS-RELATED FOREIGN DOCUMENTS